

Title (en)

METHODS FOR THE PRODUCTION OF COMPONENTS AND ULTRA HIGH VACUUM CVD REACTOR

Title (de)

VERFAHREN ZUR HERSTELLUNG VON BAUELEMENTEN UND ULTRAHOCHVAKUUM-CVD-REAKTOR

Title (fr)

PROCEDE DE FABRICATION DE COMPOSANTS ET REACTEUR DE DEPOT CHIMIQUE EN PHASE VAPEUR A VIDE POUSSE

Publication

**EP 1434898 A1 20040707 (DE)**

Application

**EP 02754096 A 20020828**

Priority

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Abstract (en)

[origin: WO03031680A1] In order to commercially treat components by CVD, whilst retaining ultra high vacuum residual gas conditions, the components are introduced into a CVD reactor (1), which meets the necessary requirements, in the form of a batch, from a vacuum transport chamber (13) which connects said UHV-CVD reactor (1) with a pre-arranged serial treatment chamber (17). The treatment chamber (17) can be a lock chamber, a further vacuum transport chamber, a coating chamber, a cleaning chamber, an etching chamber, a heating chamber, a buffer chamber or an implantation chamber.

IPC 1-7

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IPC 8 full level

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